## Development of a Scalable Spring Contact for Probe Cards

#### **Southwest Test Workshop 2000**



FormFactor Inc. 2140 Research Drive Livermore CA, 94550

www.formfactor.com June 12, 2000



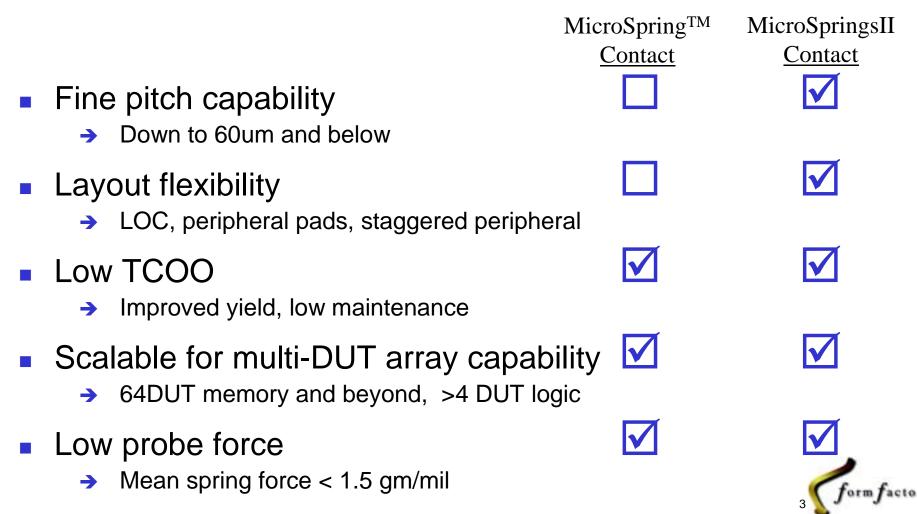


## Agenda

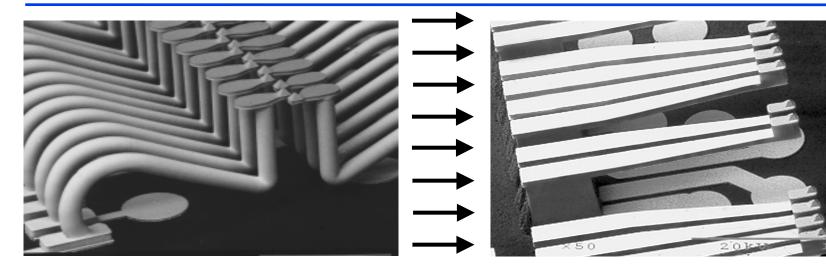
- Probe Card Requirements
- FormFactor Current Status
- Introducing MicroSprings<sup>TTM</sup> contact
- MicroSpringsII technology characterization
- Beta test results
- Conclusions



# **Probe Card Requirements**



### MicroSpring vs. MicroSprings TContact



#### What is the **SAME**

- Truncated pyramid contact
  - → ProbeAlloy<sup>TM</sup> contact metallurgy
- Probe card construction
  - → PCB
  - ➔ Interposer
  - → Ceramic space transformer
- Electrical characteristics

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#### What is **NEW**

- Cantilever type spring
- Better pitch capability
  - → 90µm NOW 60µm 2001

May 18, 2000

- Increased layout flexibility
- Better control of spring force

## MicroSpringsII Production Proven Contact Technology

- FormFactor ProbeAlloy<sup>TM</sup> contacts
- Truncated pyramid contact
- Low contact resistance
- Minimal cleaning
- Long lifetime
- Production proven over millions of touchdowns at over 20 customer sites



# MicroSprings **T** Characterization

- 200,000 touchdowns reliability test
- 100,000 touchdowns Cres test
- Cres vs overtravel
- Scrub mark characteristics
- Spring force



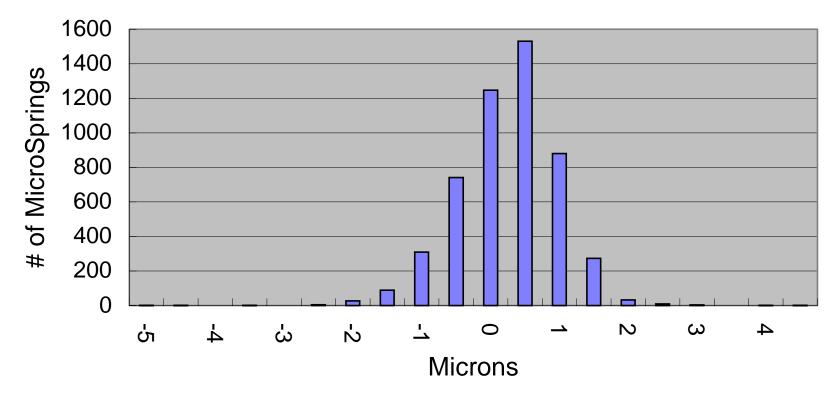
# 200,000 Touchdown Reliability Test

- 732 spring probe card
- Performed touchdowns on TSK UF-200
  - Average 87um overtravel from first contact
  - Used FFI wafer non-abrasive contact surface
- Measured probe tip x, y, and planarity on API PRVX1
  - Measured at:

0	25,000
1,000	50,000
5,000	100,000
10,000	200,000
touchdowns	



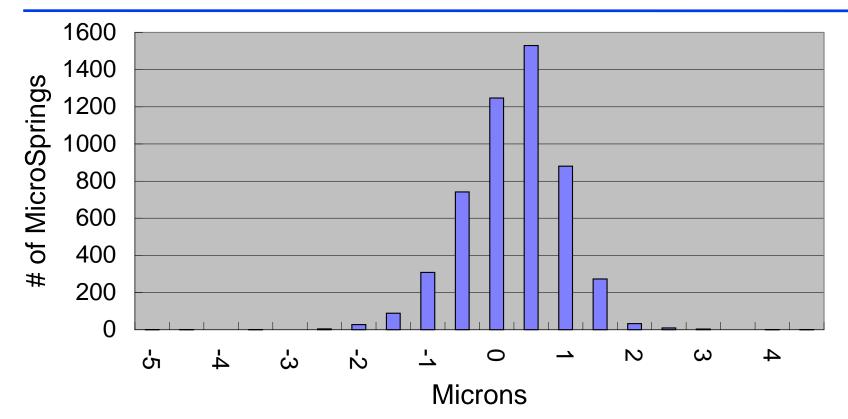
#### Change in X Alignment After 200,000 Touchdowns



•736 probes x 7 measurements = 5152 data points
•Maximum deviation from initial position over 200k touchdowns
•Measured on API PRVX – specified measurement error ±1.3um
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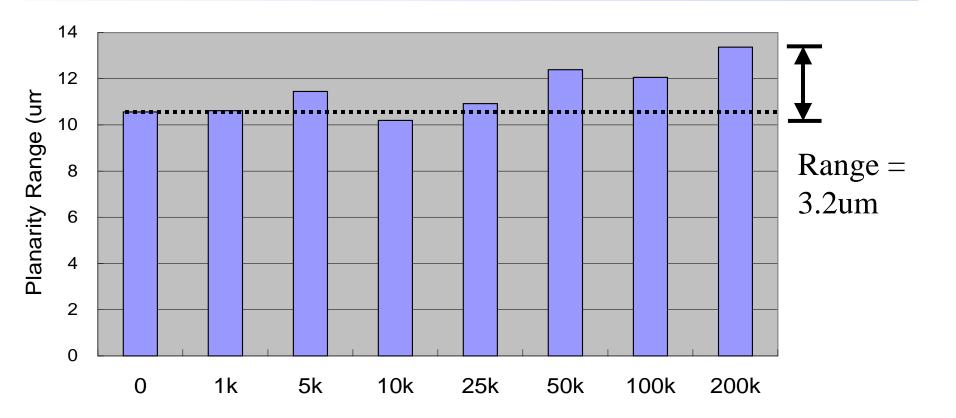
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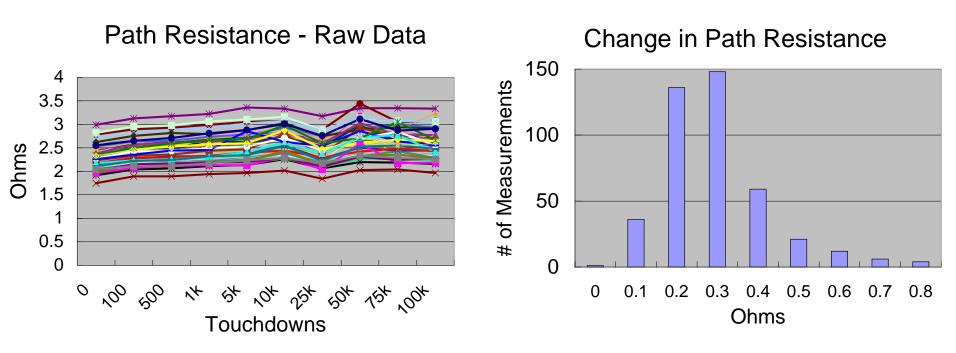
#### **Change in Planarity Over 200,000 Touchdowns**



•736 probes measured •Measured on API PRVX – specified measurement error ±1.3um Southwest Test Workshop 2000



#### 100,000 Touchdowns vs. Path Resistance



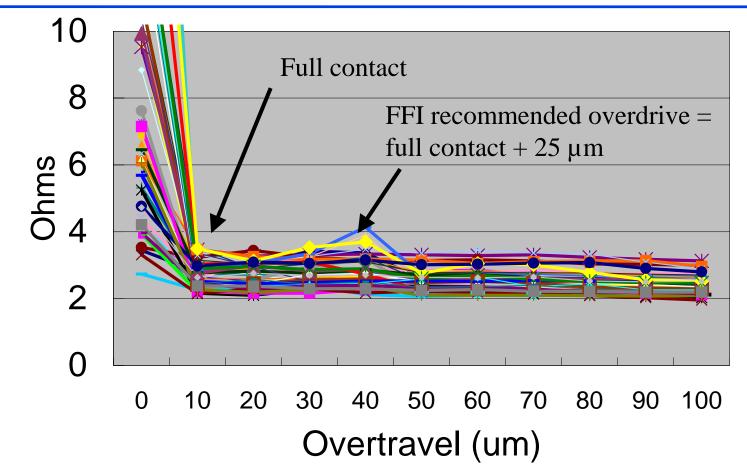
•48 probes monitored – 20 mA forcing current

•Customer supplied Al/Cu wafers

•Tested at 85°C



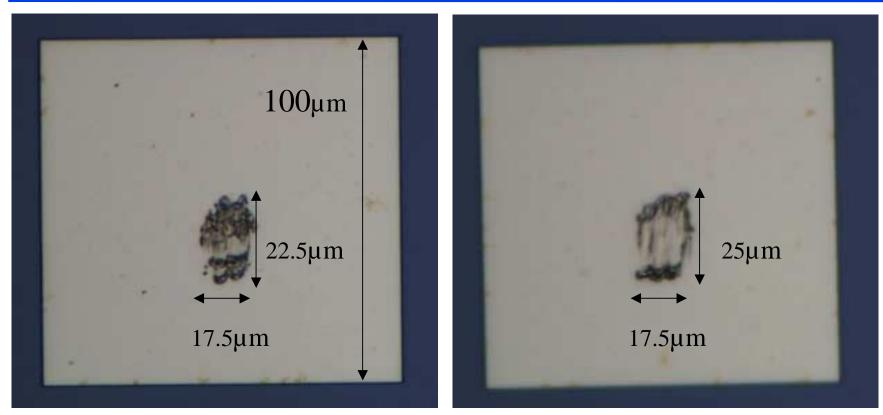
## Path Resistance vs Overtravel



- •48 probes measured- 20mA forcing current
- Customer supplied Al/Cu wafers
- •Tested at 85°C



## **Scrub Mark**



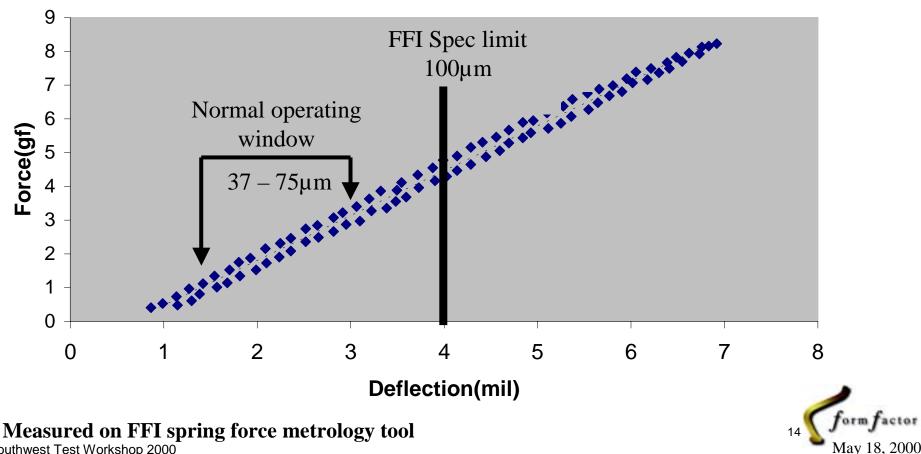
Scrub Mark at 40µm overtravel 17.5 x 22.5µm scrub in 100µm pad Scrub Mark at 80 $\mu$ m overtravel 17.5 x 25 $\mu$ m scrub in 100 $\mu$ m pad

May 18, 2000

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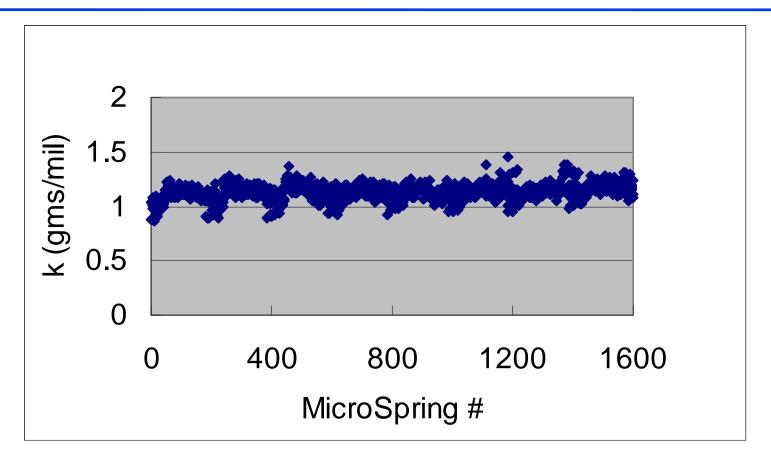
# **Spring Characteristics**

#### **Force vs Deflection Curve**



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## Spring Constant – k



MicroSpringsII – 1600 springs, Mean k = 1.13, Range = 0.57

Measured on FFI spring force metrology tool Southwest Test Workshop 2000



# FORMFACTOR, INC. MicroSpringsII Beta Testing – Customer #1

- 32DUT card passed correlation with existing MicroSpring probe card – equivalent yield
- > 50,000 production touchdowns with no cleaning
- Card examined @ FFI after 30,000 touchdowns no change

	X Error (μm )	Y Error (μm )	Planarity (μm )
Initial*	13.8	18.9	19.7
After 30K Touchdowns**	18.9	16.7	24.9
Change	+5.1	-2.2	+5.2

\*Total Range of data (max - min), 32DUT probe card, 1472 Microsprings

\*\* API Motherboard was NOT fine leveled for the "Initial" measurement

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## FORMFACTOR, INC. MicroSpringII Beta Testing – Customer #2

- 4 DUT logic probe card
- 4 DUT probe card correlated to single DUT cantilever probe card
- MicroSpringII advantages:
  - I space transformer can be used for single, dual or 4 DUT probing
  - Better decoupling
  - Low cleaning frequency
  - Smaller scrub marks



# Conclusions

- Characterization shows robust new MicroSpring contact
- Beta results confirm characterization results
- MicroSpringII technology is in production in parallel memory and logic applications
- FFI MicroSpringII technology is now available for fine pitch probing

